

Anthony G Fowler

List of Publications by Year in descending order

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citing authors

#	ARTICLE	IF	CITATIONS
1	\$Q\$ Control of an Active AFM Cantilever With Differential Sensing Configuration. IEEE Transactions on Control Systems Technology, 2019, 27, 2271-2278.	5.2	23
2	On-Chip Dynamic Mode Atomic Force Microscopy: A Silicon-on-Insulator MEMS Approach. Journal of Microelectromechanical Systems, 2017, 26, 215-225.	2.5	33
3	MEMS for Nanopositioning: Design and Applications. Journal of Microelectromechanical Systems, 2017, 26, 469-500.	2.5	34
4	On-Chip Feedthrough Cancellation Methods for Microfabricated AFM Cantilevers With Integrated Piezoelectric Transducers. Journal of Microelectromechanical Systems, 2017, 26, 1287-1297.	2.5	25
5	Q control of a microfabricated piezoelectric cantilever with on-chip feedthrough cancellation. , 2017, , .		4
6	A 4-DOF MEMS Energy Harvester Using Ultrasonic Excitation. IEEE Sensors Journal, 2016, 16, 7774-7783.	4.7	3
7	Internal Model Control for Spiral Trajectory Tracking With MEMS AFM Scanners. IEEE Transactions on Control Systems Technology, 2016, 24, 1717-1728.	5.2	30
8	Note: A silicon-on-insulator microelectromechanical systems probe scanner for on-chip atomic force microscopy. Review of Scientific Instruments, 2015, 86, 046107.	1.3	6
9	Tracking of spiral trajectories beyond scanner resonance frequency by a MEMS nanopositioner. , 2015, , .		1
10	4-DOF SOI-MEMS ultrasonic energy harvester. , 2015, , .		2
11	High-stroke silicon-on-insulator MEMS nanopositioner: Control design for non-raster scan atomic force microscopy. Review of Scientific Instruments, 2015, 86, 023705.	1.3	27
12	MEMS Nanopositioner for On-Chip Atomic Force Microscopy: A Serial Kinematic Design. Journal of Microelectromechanical Systems, 2015, 24, 1730-1740.	2.5	8
13	An Omnidirectional MEMS Ultrasonic Energy Harvester for Implanted Devices. Journal of Microelectromechanical Systems, 2014, 23, 1454-1462.	2.5	25
14	Control of a Novel 2-DoF MEMS Nanopositioner With Electrothermal Actuation and Sensing. IEEE Transactions on Control Systems Technology, 2014, 22, 1486-1497.	5.2	27
15	A MEMS electromagnetic energy harvester using ultrasonic excitation. , 2013, , .		0
16	Design and Analysis of Nonuniformly Shaped Heaters for Improved MEMS-Based Electrothermal Displacement Sensing. Journal of Microelectromechanical Systems, 2013, 22, 687-694.	2.5	22
17	Nonlinear analysis of electrothermal position sensors with contoured heaters. , 2013, , .		1
18	Design and Characterization of a 2-DOF MEMS Ultrasonic Energy Harvester With Triangular Electrostatic Electrodes. IEEE Electron Device Letters, 2013, 34, 1421-1423.	3.9	6

#	ARTICLE	IF	CITATIONS
19	Characterization of a 2-DoF MEMS nanopositioner with integrated electrothermal actuation and sensing. , 2012, , .		2
20	A 3-DoF MEMS ultrasonic energy harvester. , 2012, , .		10